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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Applicants : Eiju KOMURO et al.

Group Art Unit : 2812

Appl. No. : 10/811,812

Examiner : Not Yet Assigned

Filed : March 30, 2004

Confirmation No. : 2851

For : METHOD OF MANUFACTURING A PIEZOELECTRIC THIN FILM
RESONATOR, MANUFACTURING APPARATUS FOR A
PIEZOELECTRIC THIN FILM RESONATOR, PIEZOELECTRIC
THIN FILM RESONATOR, AND ELECTRONIC COMPONENT

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir :

In accordance with the duty of disclosure under 37 C.F.R. §1.56 and §§1.97-1.98,

Applicants hereby call to the Examiner's attention the following documents:

Japanese Laid-Open Patent Publication No. 2001-251159, which was published
on September 14, 2001, together with an English language Abstract of the same.

Applicants note that this document is mentioned on page 1 of the specification of the
present application;

Japanese Laid-Open Patent Publication No. SHO 58-137317, which was
published on August 15, 1983, together with an English language Abstract of the same;

Japanese Laid-Open Patent Publication No. SHO 58-153412, which was
published on September 12, 1983, together with an English language Abstract of the
same;

Japanese Laid-Open Patent Publication No. SHO 60-171822, which was published on September 5, 1985, together with an English language Abstract of the same;

Japanese Laid-Open Patent Publication No. HEI 9-64683, which was published on March 7, 1997, together with an English language Abstract of the same; and

Japanese Laid-Open Patent Publication No. HEI 10-200354, which was published on July 31, 1998, together with an English language Abstract of the same.

Applicants respectfully request that the Examiner consider the above material and cite the same. Copies of the above-noted foreign documents are attached hereto and are listed on the attached PTO-1449 Form. The Examiner is requested to initial the appropriate spaces on the attached Form and to return a copy of the completed Form to the Applicants with the next official communication in the present application.

Applicants also bring to the Examiner's attention the following co-pending, commonly assigned patent application:

U.S. Patent Application No. 10/819,134 to KOMURO, entitled "Method of Manufacturing a Piezoelectric Thin Film Resonator, Manufacturing Apparatus for a Piezoelectric Thin Film Resonator, Piezoelectric Thin Film Resonator, and Electronic Component," which was filed on April 7, 2004.

In accordance with 37 C.F.R. §1.98 (a)(2)(iii), a copy of the above-noted application is attached. However, the Examiner is also requested to review the file wrapper of this U.S. patent application at the U.S. Patent and Trademark Office and the references of record, if any, cited therein.

Applicants note that an Office Action on the merits has not issued in the present application, and thus no fee is believed necessary to ensure consideration of the submitted material.

Should the Examiner have any questions, the Examiner is invited to contact the undersigned at the below-listed telephone number.

Respectfully Submitted,
Eiju KOMURO et al.

Will: Boshme
Reg. No. 44,550

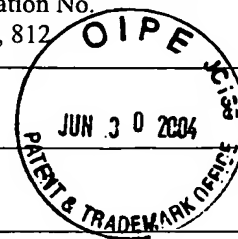
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Application No.
10/811, 812

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Group
2812

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		DOCUMENT NUMBER								DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO	
200	1	-	2	5	1	1	5	9	09/14/01	JAPAN					
5	8	-	1	3	7	3	1	7	08/15/83	JAPAN					
5	8	-	1	5	3	4	1	2	09/12/83	JAPAN					
6	0	-	1	7	1	8	2	2	09/05/85	JAPAN					
		9	-	6	4	6	8	3	03/07/97	JAPAN					
1	0	-	2	0	0	3	5	4	07/31/98	JAPAN					

	1	English language Abstract of JP 2001-251159.
	2	English language Abstract of JP 58-137317.
	3	English language Abstract of JP 58-153412.
	4	English language Abstract of JP 60-171822.
	5	English language Abstract of JP 9-64683.
	6	English language Abstract of JP 10-200354.

DATE CONSIDERED

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.